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Substitute for form 1449A/B/PTO

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet	1	of	1
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**Complete if Known**

Application Number	Unassigned
Filing Date	August 22, 2001
First Named Inventor	Shintani
Group Art Unit	Unassigned
Examiner Name	Unassigned
Attorney Docket Number	401352

## U.S. PATENT DOCUMENTS

[illegible]

**FOREIGN PATENT DOCUMENTS**

[illegible]

## OTHER - NON PATENT LITERATURE DOCUMENTS

OTHER - NON PATENT LITERATURE DOCUMENTS				
Examiner Initials	Doc. No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number (s), publisher, city and/or country where published.	Translation	
			Yes	No*
K-CC	A1	Watanabe et al., "Selective Etching Of Phosphosilicate Glass With Low Pressure Vapor HF", Journal of the Electrochemical Society, Volume 142, Number 1, January 1995, pages 237-243	X	
K-CC	A2	Wong et al., "Characterization Of Wafer Cleaning And Oxide Etching Using Vapor-Phase Hydrogen Fluoride", Journal of the Electrochemical Society, Volume 138, Number 8, June 1991, pages 1799-1802	X	
K-CC	A3	Miki et al., "Gas-Phase Selective Etching Of Native Oxide", IEEE Transactions on Electron Devices, Volume 37, Number 1, January 1990, pages 107-115	X	

Examiner Signature \_\_\_\_\_

K. C. O'Brien.

Date Considered

10-21-03

- + An English-language equivalent/patent, or an English-language abstract, or an English-language version of the search report or action by a foreign patent office in a counterpart foreign application indicating the degree of relevance found by the foreign office is being submitted in lieu of a concise explanation of relevance under 37 CFR 1.98(a)(3).